

# INTERNATIONAL STANDARD



**Semiconductor devices – Micro-electromechanical devices –  
Part 48: Test method for determining solution concentration by optical  
absorption using MEMS fluidic device**



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## INTERNATIONAL ELECTROTECHNICAL COMMISSION

SEMICONDUCTOR DEVICES –  
MICRO-ELECTROMECHANICAL DEVICES –

**Part 48: Test method for determining solution concentration  
by optical absorption using MEMS fluidic device**

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The language used for the development of this International Standard is English.

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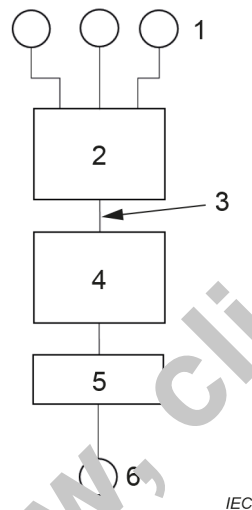
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## INTRODUCTION

A MEMS fluidic device is one of the key devices in MEMS technologies, including bio-MEMS, chemical MEMS, and micro TAS (total analytical system). A MEMS fluidic device, in general, consists of several micro components such as inlet ports for injection of a filtered sample and reagents to induce a sample to have the optical absorption at specific wavelength, a microfluidic mixer for physical mixing, a micro-reactor for chemical or biological reaction, a detection area for determining the concentration of solution using optical source and detector from the outside, as well as outlet ports for waste-out as shown in Figure 1. All components in a MEMS fluidic device are connected with microfluidic channels. In case there is a synthesizing solution with absorption at a specific wavelength in a MEMS fluidic device, it is possible to determine the concentration by using an absorption method at specific absorption wavelength based on the Beer-Lambert law [1]<sup>1</sup>. MEMS fluidic devices are more cost-effective than conventional analysis tools and methods since expensive reagents and human power are used less and in situ monitoring is enabled.



### Key

- 1 inlet ports
- 2 microfluidic mixer
- 3 microfluidic channel
- 4 micro-reactor
- 5 detection area
- 6 outlet port

**Figure 1** - Schematic drawing of micro components in a MEMS fluidic device (top view)

<sup>1</sup> Numbers in square brackets refer to the Bibliography.

# SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –

## Part 48: Test method for determining solution concentration by optical absorption using MEMS fluidic device

### 1 Scope

This part of IEC 62047 specifies the requirements and testing method to determine the solution concentration by optical absorption using MEMS fluidic device.

### 2 Normative references

There are no normative references in this document.

### 3 Terms and definitions

For the purposes of this document, the following terms and definitions apply.

ISO and IEC maintain terminology databases for use in standardization at the following addresses:

- IEC Electropedia: available at <https://www.electropedia.org/>
- ISO Online browsing platform: available at <https://www.iso.org/obp>

#### 3.1

##### **microfluidic mixer**

MEMS fluidic device for mixing more than two liquid samples in microfluidic channel and chamber

#### 3.2

##### **MEMS fluidic channel** **microfluidic channel**

channel in sub-micron or micron dimension to deliver liquid or gas, fabricated usually by micromachining or MEMS techniques

### 4 Test method

#### 4.1 General

##### 4.1.1 Principle of the absorption method

The principle of the absorption method for determining the concentration of a solution is based on the Beer-Lambert law. As shown in Figure 2, Beer-Lambert law relates the optical attenuation of a physical material containing a single attenuating species of uniform concentration to the optical path length through the sample and absorptivity of the species with the following Formula (1):

$$A = -\log T = \log(1/T) = a \cdot b \cdot c \quad (1)$$